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On January 10, 2005

TOWNSEND and TOWNSEND and CREW LLP

By: 
Tiffany Wu

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Chien Hua Chen et al.

Application No.: 10/796,700

Filed: March 8, 2004

For: METHOD FOR OPERATING
CHEMICAL MECHANICAL
POLISHING ("CMP") TOOL FOR
THE MANUFACTURE OF
SEMICONDUCTOR DEVICES

Examiner: Everhart, Caridad

Art Unit: 2825

PETITION REQUESTING ENTRY OF
CERTIFIED FOREIGN PRIORITY
DOCUMENT UNDER M.P.E.P.
§ 201.14(a) AND 37 C.F.R. § 1.55

Box Issue Fee
Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

Please enter the attached certified copy of Chinese Patent Application

No. 02160568.8, filed on December 30, 2002. This priority document is referenced in the

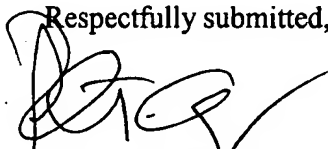
Declaration signed by the inventors, Chien Hua Chen, Yuan Hsin Peng, and Xiao Hua Li, as

filed in the subject application on March 8, 2004.

09/26/2005 AKELLEY 00000017 201430 10796700

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This Petition is filed after payment of the issue fee, and prior to issue of the application. To perfect a claim of priority to the attached foreign application under 35 U.S.C. § 119, the Patent Office is hereby authorized to deduct the Petition Fee of \$130.00 as set forth in § 1.17(i) from Deposit Account No. 20-1430. This Petition is filed in duplicate.

Respectfully submitted,

Richard T. Ogawa
Reg. No. 37,692

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